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PATENT
Attorney Docket No.: A5771/T42200

Assistant Commissioner for Patents
Washington, D.C. 20231

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On: 7/12/02
TOWNSEND and TOWNSEND and CREW LLP

By: [Signature]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

ZHENGQUAN TAN et al.

Application No.: 09/854,083

Filed: May 11, 2001

For: HDP-CVD DEPOSITION
PROCESS FOR FILLING HIGH
ASPECT RATIO GAPS

Examiner: William D. Coleman

Art Unit: 2823

AMENDMENT

BOX FEE AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action mailed April 18, 2002, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Please replace the paragraph beginning at line 25 of page 8 with the following rewritten paragraph:

al --Gas ring 37 also has a plurality of gas nozzles 40 (only one of which is shown), which in a preferred embodiment are co-planar with and shorter than source gas nozzles 39, and in one embodiment receive gas from body plenum 41. Gas nozzles 39 and 40 are not fluidly coupled in some embodiments it is desirable not to mix gases before injecting the gases into chamber 13. In other embodiments, gases may be mixed prior to injecting the gases into chamber 13 by providing apertures (not shown) between body plenum 41 and gas ring plenum 36. In one embodiment, third and fourth gas sources, 34C and 34D, and third and fourth gas flow controllers, 35C' and 35D', provide gas to body plenum via gas delivery lines 38.

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